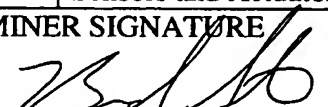


<b>FORM PTO-1449 MODIFIED</b>  <b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION</b>				Docket No.: I431.101.101 (2002P15009US)		Application No.: Unknown	
				APPLICANT: Andreas Meckes et al.  FILING DATE: Herewith  GROUP ART UNIT: Unknown			
<b>U.S. PATENT DOCUMENTS</b>							
EXAMINER INITIAL	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
<i>BKS</i> ↓	4,744,863	05-1988	Guckel et al.				
	5,090,254	02-1992	Guckel et al.				
	5,454,906	10-1995	Baker et al.				
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	2001/0004085	06-2001	Gueissaz				
	6,550,664	04-2003	Bradley et al.				
<b>FOREIGN PATENT DOCUMENTS</b>							
EXAMINER INITIAL	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES	TRANSLATION NO
<i>BKS</i>	101 05 351 A 1	08-2002	DE			X	
<b>OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, etc.)</b>							
<i>BKS</i>	Mei et al., "Process Characterization and Analysis of Sealed Vacuum Microelectric Devices," J. Vac. Sci. Techn. B 12(2), March/April 1994, pp. 638-643.						
<i>BKS</i>	Hakan Ederstig, Per Wallgren, "Spin Desposition of Polymers over Holes and Cavities," Sensors and Actuators A46-47, 1995, pp. 95-97.						
EXAMINER SIGNATURE 				DATE CONSIDERED 10/3/05			
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.							